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Investigation of the flow rate effect on the plasma parameters by using miniaturized plasma diagnostic device in the remote plasma.
HYUN-DONG EO, JIN-YOUG KIM, CHIN-WOOK CHUNG, Department of electrical engineering, Hanyang university — Miniaturized plasma diagnostic device was developed for installing near the remote plasma source because there is a little space for the monitoring system. Miniaturized plasma diagnostic device can be used like a gauge without additional connection with measuring instrument and computer. Miniaturized plasma diagnostic device used the floating harmonic method that used for obtaining plasma parameters such as electron temperature and ion density. Experiments were conducted to measure plasma parameters in the remote source with wall probe. As increasing the flow rate of the remote source, the increase of the ion density and electron temperature is observed by using our device.

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